

AF/2882
DRJ

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Application No.: 09/769,490

Filed: January 26, 2001



: Response Under 37 CFR 1.116 - Expedited Procedure

: Customer Number: 20277

: Confirmation Number: 5521

: Group Art Unit: 2882

: Examiner: Kao, Chih Cheng G.

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR,
SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR
DEVICE

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above-identified application.

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☐

No additional fee is required.

Applicant is entitled to small entity status under 37 CFR 1.27

Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	8	48	0	\$50.00 =	\$0.00
Independent Claims	8	12	0	\$200.00 =	\$0.00
Multiple claims newly presented					\$0.00
Fee for extension of time					\$0.00
					\$0.00
Total of Above Calculations					\$0.00

☐ Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.

☒ The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP

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Date: December 20, 2004

Please recognize our Customer No. 20277 as our
correspondence address.



Docket No.: 49657-961

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

:Response Under 37 CFR 1.116-Expedited Procedure

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Filed: January 26, 2001

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK,
X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON
RADIATION METHOD AND SEMICONDUCTOR DEVICE

AMENDMENT UNDER 37 C.F.R. § 1.116

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Final Office

Action dated September 20, 2004, pursuant to the provisions of 37 C.F.R. § 1.116.